



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	§	
Chen et al.	§	Group Art Unit: 1746
	§	
Serial No. 10/712,460	§	Examiner: To be determined
	§	
Filed: 11/13/2003	§	Customer No.: 000042717
	§	
For: Semiconductor Wafer	§	Attorney Docket No.:
Manufacturing Methods	§	TSMC2002-1015/24061.42
Employing Cleaning Delay Period	§	

**PRELIMINARY AMENDMENT**

Mail Stop Amendment  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Prior to examination, please amend the above-identified patent application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Remarks** begin on page 3 of this paper.